

μ RWELL Production R&D Status

2024 / 08 / 30

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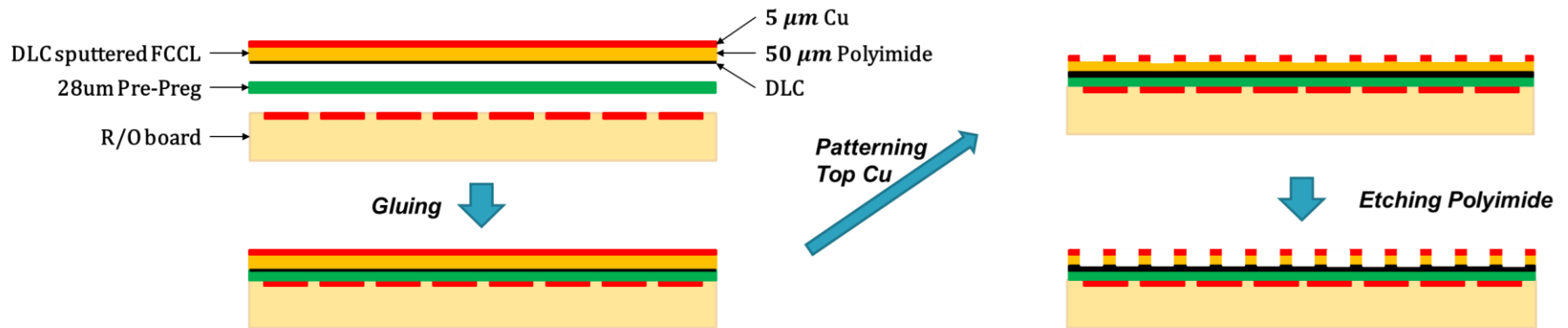
MPGD DSC Meeting

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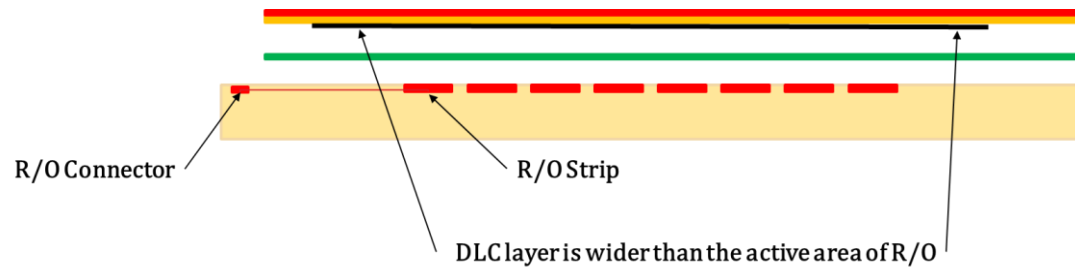
1. μ RWELL Production R&D Status

- Currently production of $10 \times 10 \text{ cm}^2$ μ RWELL is ongoing to study production feasibility
- Had a meeting with Rui in May to discuss production processes in detail
 - We are more confident that we can produce μ RWELL using the GEM facilities in Korea
- μ RWELL shares many production processes with GEM



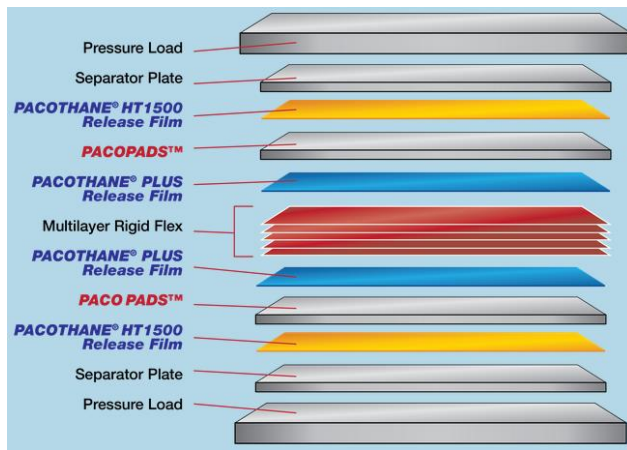
- The DLC layer is formed by a sputtering process
 - DLC-FCCL will be procured from CERN or company

1. μ RWELL Production R&D Status



- Gluing

- Pressing DLC FCCL, pre-preg and RO PCB at high temperature in a vacuum chamber
- Pressure: 7-10 bar (Not to damage FCCL)
Temperature: ~ 100-110 °C
- Flatness control is the key. Know-how to construct “stack”

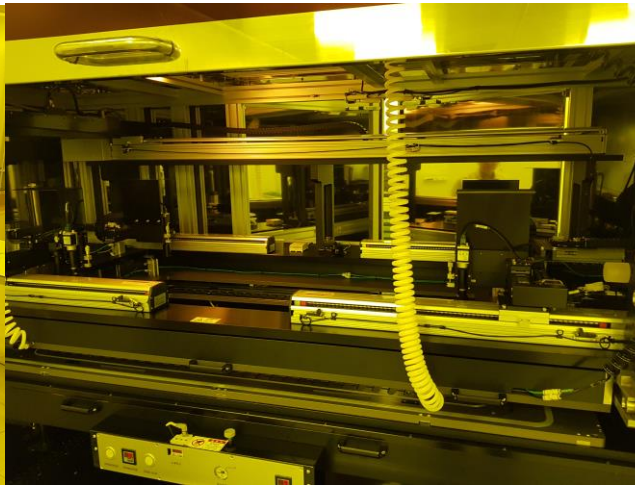
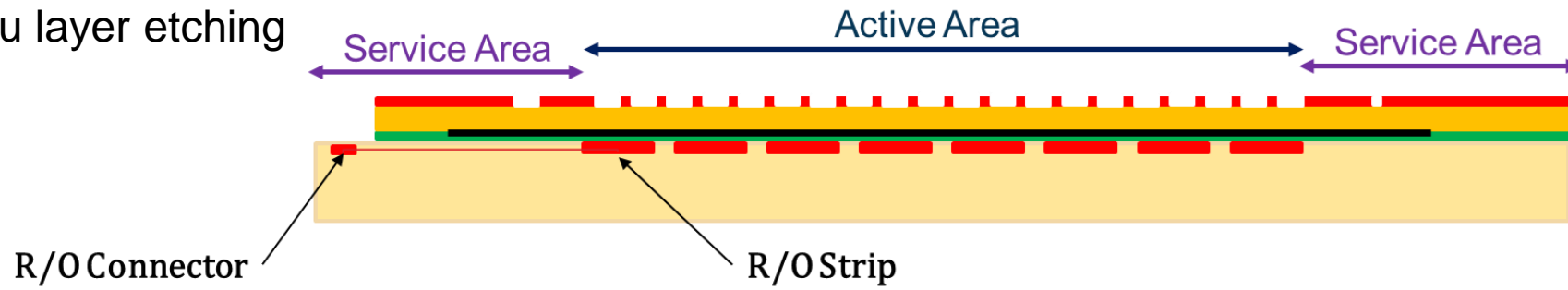


1. μ RWELL Production R&D Status

- We have looked for press companies
 - Found a company that can press up to $70 \times 70 \text{ cm}^2$ and initiated discussion
 - Enough to produce $10 \times 10 \text{ cm}^2$ μ RWELL for production process R&D
- We are still looking for companies having $1 \times 0.6 \text{ m}^2$ or larger press, but they are not common
 - How is the selection going in the semicircle or quadrant?
 - Whatever the choice, we'll try to find the $1 \times 0.6 \text{ m}^2$ press

1. μ RWELL Production R&D Status

- 1st Cu layer etching

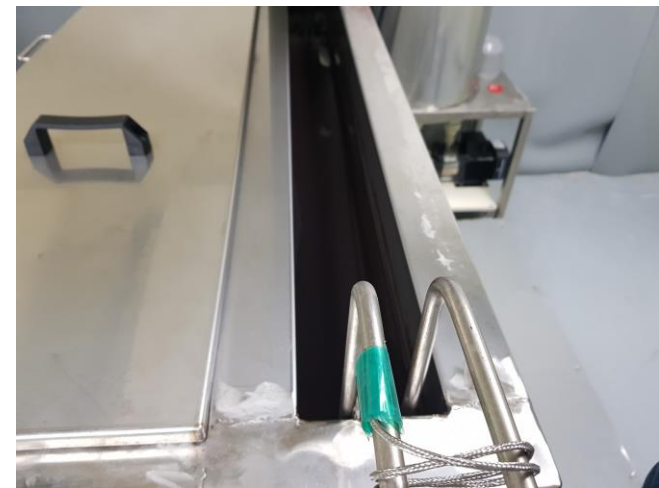
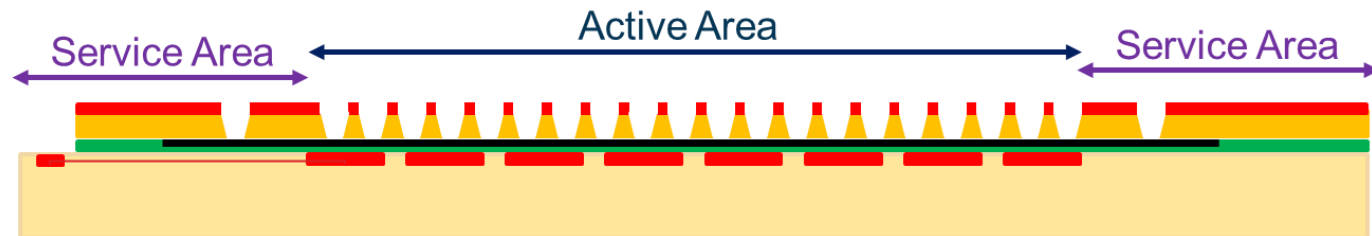


1. μ RWELL Production R&D Status

- Seed layer etching

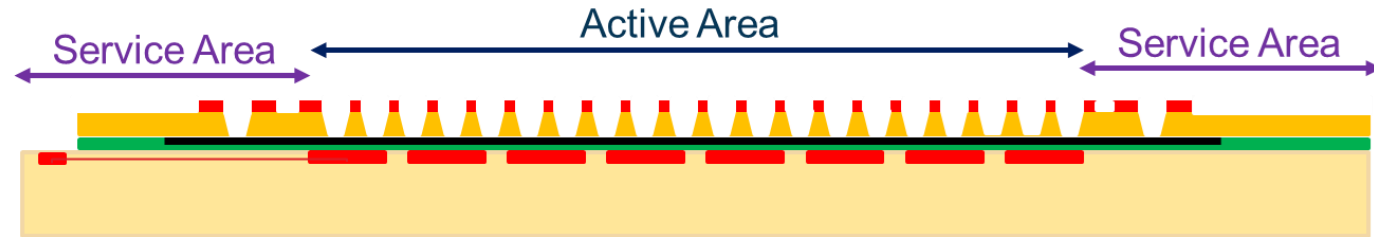


- PI layer etching
- KOH, MEA

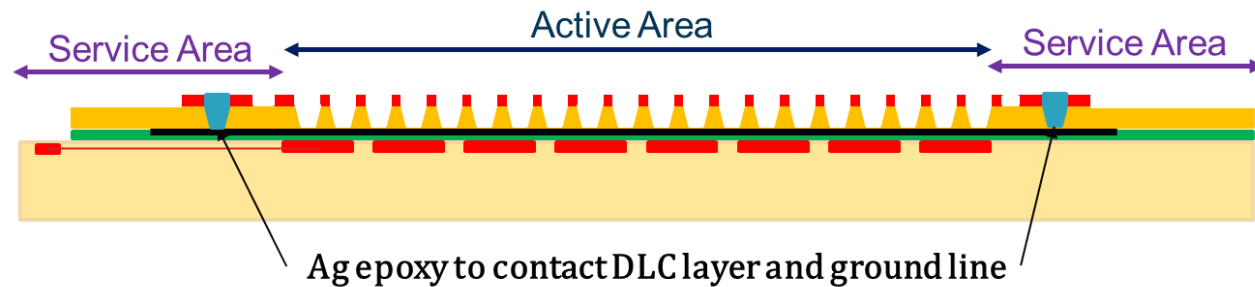


1. μ RWELL Production R&D Status

- 2nd Cu etching

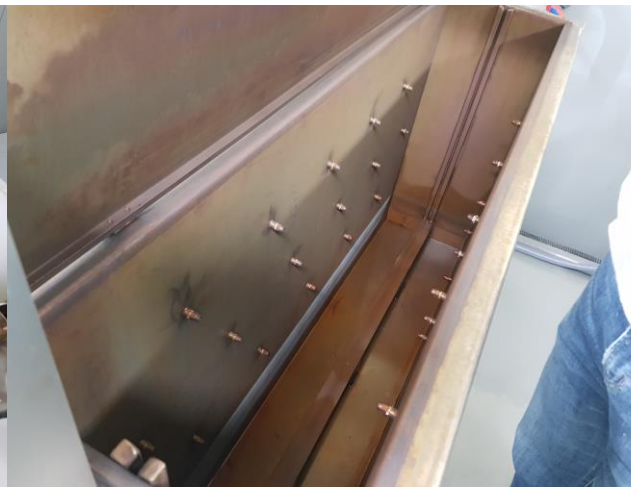
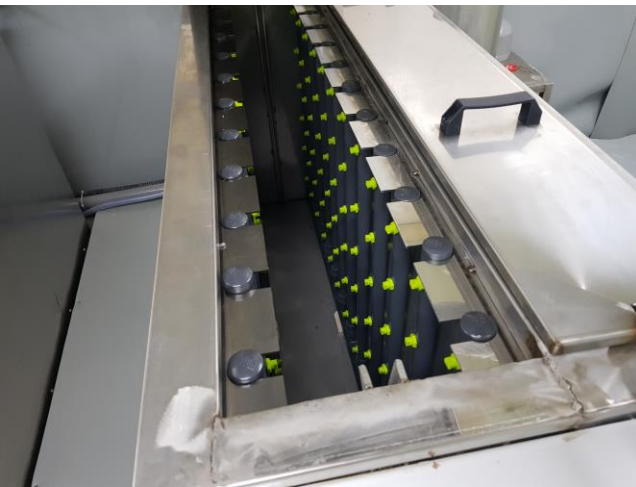


- Ag epoxy pasting to make via holes or via grooves & Soldering SMD resistors



1. μ RWELL Production R&D Status

- Cleaning
 - Chemical cleaning: surface preparation \rightarrow micro etching (sulfuric acid + hydrogen peroxide) \rightarrow neutralization (potassium permanganate) \rightarrow passivation (chromic acid) \rightarrow high pressure DI water shower
 - Electrical cleaning: controlled burning of contaminants in dry or hot environment
- If GEM or μ RWELL becomes short or sparking due to contaminants, it needs additional cleaning
 - If it has high leakage current, high pressure DI water shower would be enough



1. μ RWELL Production R&D Status

- The components to produce the $10 \times 10 \text{ cm}^2$ μ RWELL, including the DLC FCCL and RO PCB, will be shipped from CERN next month
 - Due date has been delayed
- $66 \times 66 \times 110 \text{ cm}^3$ oven has been installed in IBS area for QC and assembly

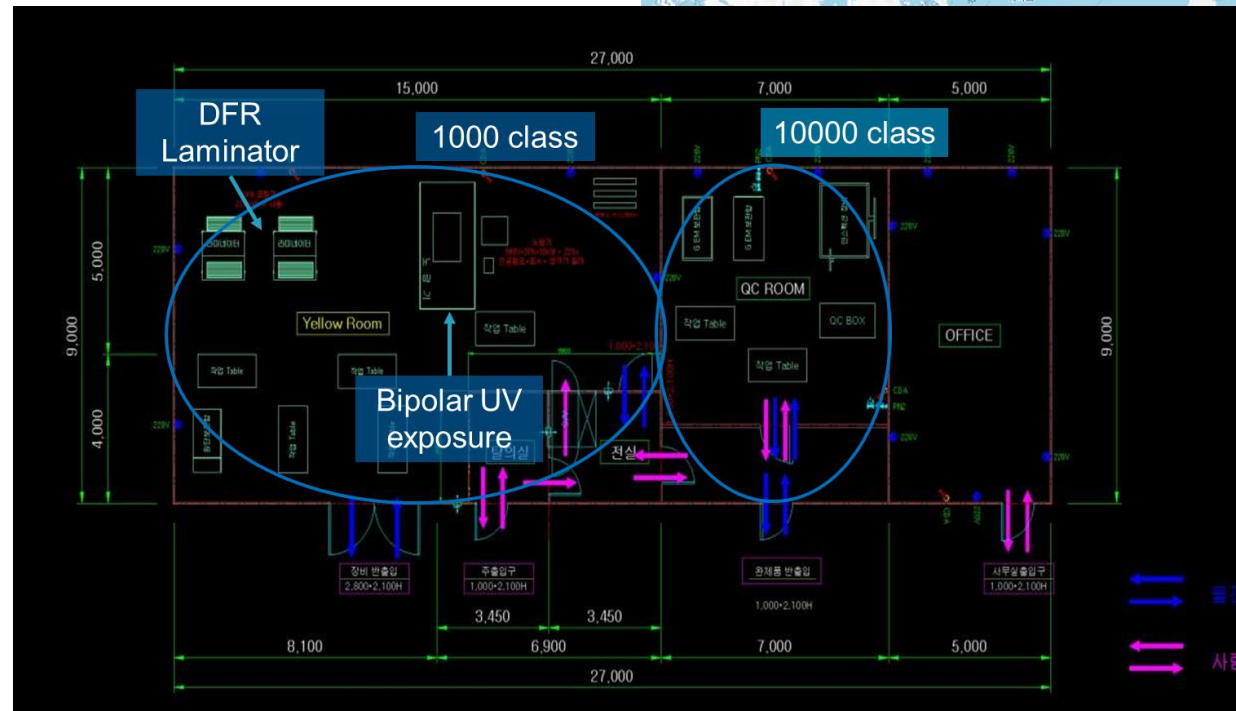
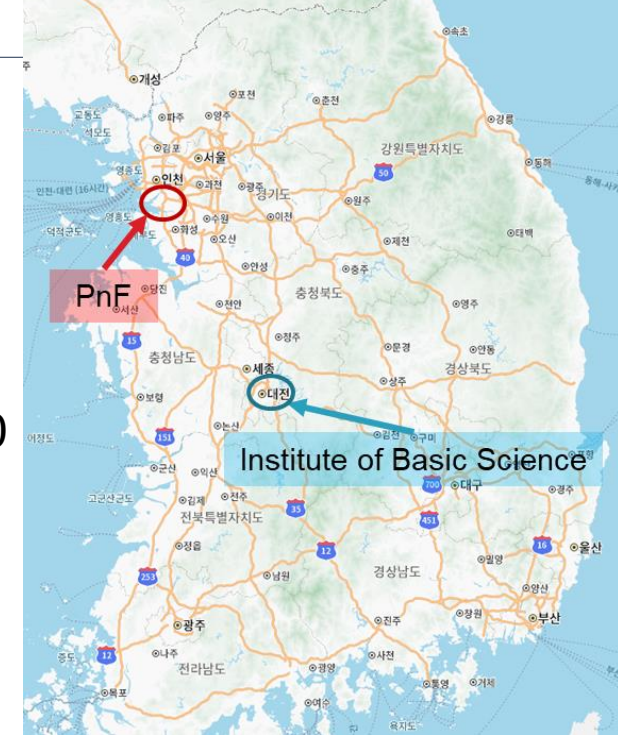


2. Contribution Plan

- In-kind contribution of GEM & μ RWELL for ECT
 - High chance to secure budget for it
- Provide assembly site
 - It is inconvenient to transport GEM and μ RWELL before assembly
 - Especially for μ RWELL, it is recommended that the production and assembly facilities are close to each other, at least the cleaning facilities
 - I think IBS in Korea is an appropriate site for the initial assembly
Here “initial” means assembly before electronics integration

2. Contribution Plan

- Institute of Basic Science: Korean version of FRIB
- Center of GEM production : photo process and QC
- Assembly in existing 1000 class room or upgrade 10000 class room to 1000 class



2. Contribution Plan

- If we encounter HV instability of GEM or μ RWELL especially during assembly, we can send it to PnF to handle it
- We're also considering moving the cleaning equipment into the IBS
 - Not feasible to move all of it currently
 - Shouldn't be difficult to install the DI water shower and ultra sonicator
- Large pool of trained person power
- Founded for international research, IBS is a good place for hosting ECT researchers
 - Three hour from Incheon air port by public transportation
 - Dormitory

3. Budget Status

- Intensive discussion ongoing
 - Research is being commissioned to guide policy decisions and several meetings convened by the expert advisory committee are underway
- The committee is favorable to the MPGD ECT contribution plan, so the budget is likely to be secured
 - At least, the budget for GEM and μ RWELL in-kind contributions (1.5 M USD) is likely
 - Discussions are underway to secure additional funding (+1.3M USD) to host a facility for the initial assembly
- One issue is that the budget is expected to start spending in March 2026

Summary

- Production of $10 \times 10 \text{ cm}^2$ μ RWELL is ongoing to study production processes
 - Had a meeting with Rui in May
 - More confident that we can produce μ RWELL using the GEM facilities in Korea
- Contribution plan
 - In-kind contribution of GEM and μ RWELL
 - Assembly site
- Intensive discussion is ongoing about budget request
 - Budget for GEM and μ RWELL is likely
 - Discussion on additional budget for assembly site is ongoing
 - Unfortunate, the budget may start from March 2026